

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: Patrick Y. Huet et al.
Title: Process Excursion Detection
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INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria VA 22313-1450

Sir:

In compliance with 37 C.F.R. §§ 1.97 and 1.98, applicants provide this Information Disclosure Statement and accompanying form PTO-1449, listing the citations of references to be considered in the above referenced case. By this submission applicants are not admitting the materiality of these citations; they are merely submitted to ensure full compliance with 37 C.F.R. § 1.56.

Sincerely,

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By: 

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FORM PTO-1449 INFORMATION DISCLOSURE CITATIONS IN AN APPLICATION	Atty Docket:	58551.US	Serial #:
	Applicant:	Patrick Y. Huet et al.	
	Filing Date:	2003.11.19	Group:

U.S. PATENT DOCUMENTS

Examiner Initial	Cite #	Document Number	Date	Name	Class	Sub-Class	Filing Date

FOREIGN PATENT DOCUMENTS

Examiner Initial	Cite #	Document Number	Date	Country	Class	Sub-Class	Translation

OTHER NON-PATENT DOCUMENTS

Examiner Initial	Cite #	Author, title, date, pertinent pages, etc.
	1	Diebold et al., <i>Handbook of Silicon Semiconductor Metrology</i> , SEMATECH publication, year unknown, pgs 25-30 and relevant figures.

Examiner	Date Considered:
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.	

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